Radiation Report Single-Event Effects Test Report of the TPS7H2140-SEP Quad-Channel eFuse



ABSTRACT

The purpose of this study is to characterize the single-event-effects (SEE) performance due to heavy-ion irradiation of the TPS7H2140-SEP. SEE performance was verified at minimum (4.5 V) and maximum (32 V) operating conditions. Heavy-ions at an LET_{EFF} of 48 MeV × cm² / mg were used to irradiate three production devices and four pre-production devices. Flux of $\approx 10^5$ ions / cm² × s and fluences of $\approx 10^7$ ions / cm² per run were used for the characterization. The results demonstrated that the TPS7H2140-SEP is SEL and SEB/SEGR-free up to 48 MeV × cm² / mg, at T = 125°C and T = 25°C, respectively, and across the full electrical specifications. SET performance for output voltage excursions ≥ |3%| from the nominal voltage, excursions ≥ |4%| from nominal CS, and negative edge transients on the FAULT pin are discussed in Single-Event Transients (SET).

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1 Introduction

The TPS7H2140-SEP is a space-enhanced-plastic, 4.5-V to 32-V input, 5.4-A (1.35-A per channel), quadchannel eFuse. The TPS7H2140-SEP is fully protected with four integrated 160-m Ω (typical) NMOS power FETs. Full diagnostics and high-accuracy current sense enables intelligent control of the loads. An external adjustable current limit improves the reliability of whole system by limiting the inrush overload current.

The device is offered in a 28-pin HTSSOP plastic package. Table 1-1 lists general device information and test conditions. For more detailed technical specifications, user guides, and application notes, see the TPS7H2140-SEP product page.

Description ⁽¹⁾	Device Information					
TI part number	TPS7H2140-SEP					
Orderable number	TPS7H2140MPWPTSEP					
Device function	Quad-channel eFuse					
Technology	LBC8					
Exposure facility	Radiation effects facility, Cyclotron Institute, Texas A&M University (15 MeV / nucleon)					
Heavy ion fluence per run	$9.85 \times 10^6 - 1 \times 10^7$ ions/cm ²					
Irradiation temperature	25°C (for SEB/SEGR testing & SET testing), and 125°C (for SEL testing)					

Table 1-1.	Overview	Information
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2 Single-Event Effects (SEE)

The primary concern for the TPS7H2140-SEP is the robustness against the destructive single-event effects (DSEE), single-event latch-up (SEL), single-event burnout (SEB), and single-event gate rupture (SEGR). In mixed technologies such as the BiCMOS process used on the TPS7H2140-SEP, the CMOS circuitry introduces a potential for SEL susceptibility.

SEL can occur if excess current injection caused by the passage of an energetic ion is high enough to trigger the formation of a parasitic cross-coupled PNP and NPN bipolar structure, which is formed between the p-sub and n-well and n+ and p+ contacts. (For more information, see [1 and 2]). The parasitic bipolar structure initiated by a single-event creates a high-conductance path (inducing a steady-state current that is typically orders-of-magnitude higher than the normal operating current) between power and ground that persists (is "latched") until power is removed, the device is reset, or until the high-current state destroys the device. The TPS7H2140-SEP was tested for SEL at the maximum recommended voltage of 32 V and maximum load current of 5.4 A (1.35 A per channel). The device was set up with OUT₁ operating in a single configuration. OUT₂, OUT₃, and OUT₄ were operated in a parallel configuration. See Figure 6-1 for more details. The device did not exhibit SEL when heavy-ions with LET_{EFF} = 48 MeV × cm² / mg at flux ≈10⁵ ions / cm²× s, fluences of ≈10⁷ ions / cm², and a die temperature of 125°C.

Since this device is designed to conduct large currents up to 5.4 A (1.35 A per channel) and can withstand up to 32 V during the off-state, the power LDMOS introduces a potential susceptibility for SEB and SEGR (2). The TPS7H2140-SEP was evaluated for SEB and SEGR at full load conditions of 5.4 A (1.35 A per channel), and a maximum voltage of 32 V in both the enabled and disabled modes. During SEB and SEGR testing, a single current event was not observed, demonstrating that the TPS7H2140-SEP is SEB and SEGR-free up to LET_{EFF} = 48 MeV·cm²/ mg at a flux of $\approx 10^5$ ions / cm² × s, fluences of $\approx 10^7$ ions / cm², and a die temperature of $\approx 25^\circ$ C.

The TPS7H2140-SEP was characterized for SET at a flux of $\approx 10^5$ ions / cm²·s, fluences of $\approx 10^7$ ions / cm², and at room temperature. The device was characterized at IN = 4.5 V at a load of 2 A (0.5-A per channel) load. Under these conditions, the device showed three different single-event transients (SET) signatures under heavy-ion irradiation. All observed types of SETs were self-recoverable without requiring external intervention. The observed transients can be classified as:

- A brief transient of the output voltage (referred here as OUT_{X,SET}). For the purpose of this report the transients were characterize for deviations –3% ≤ OUT_X ≤ 3% from the nominal output voltage. For more details, see Section 8.
- A brief transient on the Current Sense (CS) pin. For the purpose of this report the transients were characterized for deviations –4% ≤ CS ≤ 4% from the nominal output voltage. This type of SET is referred to here as CS_{SET}.
- 3. A FAULT upset \geq 1 V from nominal on a negative-edge trigger.



3 Device and Test Board Information

The TPS7H2140-SEP is packaged in a 28-pin HTSSOP plastic package as shown in Figure 3-1. An evaluation board designed for radiation testing was used to evaluate the performance and characteristics of the TPS7H2140-SEP under heavy-ions. Figure 3-2 shows the top view of the evaluation board used for the radiation testing. Figure 3-3 shows the EVM board schematics used for the heavy-ion testing campaign.



The package was delidded to reveal the die face for all heavy-ion testing.

Figure 3-1. Photograph of Delidded TPS7H2140-SEP [Left] and Pinout Diagram [Right]



Figure 3-2. TPS7H2140-SEP Board Top View





Figure 3-3. TPS7H2140-SEP SEE Validation EVM Schematic



4 Irradiation Facility and Setup

The heavy-ion species used for the SEE studies on this product were provided and delivered by the Texas A&M University (TAMU) Cyclotron Radiation Effects Facility using a superconducting cyclotron and an advanced electron cyclotron resonance (ECR) ion source. At the fluxes used, the ion beams had good flux stability and high irradiation uniformity over a one inch diameter circular cross-sectional area for the in-air station. Uniformity is achieved by magnetic defocusing. The flux of the beam is regulated over a broad range spanning several orders of magnitude. For the majority of these studies, ion flux of 10^5 ions / cm² × s were used to provide heavy-ion fluences of approximately 10^7 ions / cm².

For the experiments conducted in this report, the following ions and corresponding angles were used to provide a range of LET_{EFF} of 48 MeV × cm2 / mg.

- Silver (¹⁰⁹Ag) at 0° for an LET_{EFF} = 48 MeV
 - Range_{EFF} = 91.2 μ m
 - Total Kinetic Energy = 1.634 GeV (15 MeV / nucleon)

Ion uniformity for these experiments was between 93 and 96%.

Figure 4-1 shows the TPS7H2140-SEP test board used for the experiments at the TAMU facility. Although not visible in this photo, the beam port has a 1-mil Aramica window to allow in-air testing while maintaining the vacuum within the accelerator with only minor ion energy loss. The in-air gap between the device and the ion beam port window was maintained at 40 millimeters for all runs.



Figure 4-1. Photograph of the TPS7H2140-SEP Evaluation Board Mounted in Front of the Heavy-Ion Beam Exit Port at the Texas A&M Cyclotron Radiation Effects Facility

5 Depth, Range, and LET_{EFF} Calculation

Tin Barrier	😽 Seuss 2022					×
MetDCU	Current settings	Cyclotron operator controls		User controls		
Tin Barrier	Log file: CI-TAMU Feb 2020	Enable	Open S1 Close S1	Layers: Define	Load Edit	Reports (click to view):
Oxide	Beam: 15.0 MeV/u 109Ag @ K500	Select Log File	Open S2 Close S2	Control Positioning	Set Run Parameters	User file contents Run summary
Metal 4	Al degrader (mil): 0.000	Upload User Files	Set Hardware Check Beam	Set Options	_	Layer details Log file User ontions
Ti+Tin Barrier	Layers: 4 (TPS7H2140) Summary	Select Beam	Detector shield	Help	Bun	Current settings Range table
ILD 3	Beam energy (MeV/u): 10.5	Set Bias Update		Comment:		Beam history
Ti+Tin Barrier	Beam energy (MeV): 1144	Lnange Setup	Exit Program		To Log File To I	Run File To Screen
Metal 3	Target substrate: silicon	CYCLOTRO	N INSTITUTE	Calibration factor:		
	Nominal LET (MeVcm²/mg): 46.8	Radiation Effec	cts Testing Facility	Measure	Set	Lock T=0
Ti+Tin Barrier	Nominal range (µm): 99.6	Positioning coordinates	Beam characteristics			
Metal 2	Effective LET (MeVcm²/mg): 46.8	× -0.000 in	Flux (ions/(cm ² s)):	2.36E+004 TL	2294	2333 TR
Ti+Tin Barrier	Effective range (µm): 99.6	Y -0.000 in	Lipiformity (%):	07		
ILD 1	DUT location: In-air	Z 10.000 cm				
Ti+Tin Barrier	DUT position: Current	T -0.000 deg	Central shift (%):	1 BL	2446	2327 BR
Metal 1	Bias (∀): 480 480 480 480 480	U 1.500 deg	Axial gain:	9.81E-001		
Oxide	,	y 1.500 in	Calibration factor:	.00E+000		
	Beam flux control (simulation only)	0.000	Hetresh in 5354 cnts			
Silicon	Increase Decrease	S 0.000 steps	Status:			Clear
	Show Transmission Factor	R 0.000 deg				
	User: a0488733 (LT5CG017D549)				V	ladimir Horvat (C) 2006-2022

Figure 5-1. Generalized Cross-Section of the LBC8 Technology BEOL Stack on the TPS7H2140-SEP [Left] and SEUSS 2020 Application Used to Determine Key Ion Parameters [Right]

The TPS7H2140-SEP is fabricated in the TI Linear BiCMOS 250-nm process with a back-end-of-line (BEOL) stack consisting of five levels of standard thickness aluminum metal on a 0.6- μ m pitch. The total stack height from the surface of the passivation to the silicon surface is 5.46 μ m based on nominal layer thickness as shown in Figure 5-1. Accounting for energy loss through the 1-mil thick Aramica beam port window, the 40-mm air gap, and the BEOL stack over the TPS7H2140-SEP, the effective LET (LET_{EFF}) at the surface of the silicon substrate, the depth, and the ion range was determined with the SEUSS 2020 Software (provided by the Texas A&M Cyclotron Institute and based on the latest SRIM-2013 [7] models). Table 5-1 lists the results.

lon Type	Angle of Incidence	Degrader Steps (Number)	Degrader Angle	Range in Silicon	LET _{EFF} (MeV·cm²/ mg)
¹⁰⁹ Ag	0	0	0	99.2	48

Table 5-1. Krypton Ion LET_{EFF}, Depth, and Range in Silicon

6 Test Setup and Procedures

SEE testing was performed on a TPS7H2140-SEP device mounted on a TPS7H2140-SEP SEE validation board. V_{IN} , ranging from 4.5 V for SET to 32 V for SEL and SEB/SEGR, was provided to the device using the J21 (IN) and (GND) inputs with the N6766A PS Module mounted on a N6705 precision power supply in a 4-wire configuration. An external source for the I/O pins, ranging from 4.5 V for SET to 5 V for SEL and SEB/SEGR, was provided using the J33 (5 V) and (GND) inputs through channel 1 of an E36311A power supply. A second E36311A power supply, using channel 1 and channel 2, was used on TP1 (EN₁) and TP2 (EN₂) for EN_x, which ranged from 0 V for SEB Off to 4.5 V for SET testing and 5 V for all DSEE testing.

During SEL testing, the device was heated to 125°C by using a TDH35P10R0JE discrete power resistor soldered under the thermal vias on the bottom layer of the validation card. Using a PXIe-4139 SMU, a current of 1 A was forced into the power resistor elevating the die temperature to 125°C. The temperature of the die was verified using a FLIR thermal camera.

The instrument used to load the TPS7H2140-SEP was a Chroma E36300 E-Load that was used in Constant Resistance (CR) mode. The value of CR was adjusted depending on the type of test. For SEL and SEB/SEGR testing, the CR value was set to achieve a total load of 1.35 A per channel. For SET testing, the CR value was set to achieve a total load of 0.5 A per channel.

During all SEE testing, OUT_1 was operated independently while OUT_2 , OUT_3 , and OUT_4 were operated in parallel. Based on Figure 3-3, J16 and J17 were used to place EN_2 , EN_3 , and EN_4 in parallel operation while J19 and J20 were used to place OUT_2 , OUT_3 , and OUT_4 in parallel operation.

The signals monitored included OUT_1 , OUT_2 , CS, and \overline{FAULT} . OUT_1 was monitored using a MSO58B which was set to trigger on a 3% window based on the nominal value of OUT_1 . OUT_2 was monitored using a NI PXIe-5172 scope card which was set to trigger on a 3% window based on the nominal value of OUT_2 . CS was monitored using a second NI PXIe-5172 scope card which was set to trigger on a 4% window based on the nominal value of CS. FAULT was monitored using a NI PXIe-5160 scope card which was set to trigger on a negative edge trigger of 1 V less than the nominal value of FAULT.

All equipment other than the MSO58B was controlled and monitored using a custom-developed LabVIEW[™] program (PXI-RadTest) running on a HP-Z4[®] desktop computer. The computer communicates with the PXI chassis via an MXI controller and NI PXIe-8381 remote control module. The MSO58B was used using the manufacturer interface. The MSO was set to fast-frame for all SET data collection.

Table 6-1 shows the connections, limits, and compliance values used during the testing. Figure 6-1 shows a block diagram of the setup used for SEE testing of the TPS7H2140-SEP.

Pin Name	Equipment Used	Equipment Channel Used	Capability	Compliance	Range of Values Used	Trigger
IN	Agilent N6766A	Channel 3	60 V, 17 A	10-A	4.5 to 32-V	_
EN ₁	Keysight E36311A (1)	Channel 1	6 V, 5 A	0.1 A	0 to 5 V	_
EN ₂	Keysight E36311A (1)	Channel 2	25 V, 1 A	0.1 A	0 to 5 V	_
External 5-V source	Keysight E36311A (2)	Channel 1	6 V, 5 A	0.1 A	4.5 to 5 V	_
Heater	NI PXIe-4139	Channel 1	60 V, 3 A	15 V	1 A	—
OUT ₁	MSO58B	—	6.25 GS / s	—	100 MS / s	Window at ±3%
OUT ₂	NI PXIe-5172 (1)	—	100 MS / s	_	10 MS / s	Window at ±3%
CS	NI PXIe-5172 (2)	—	100 MS / s	_	10 MS / s	Window at ±4%
FAULT	NI PXIe-5160	_	100 MS/s	_	10 MS / s	Negative edge at nominal 1 V

Table 6-1. Equipment Set and Parameters used for SEE Testing the TPS7H2140-SEP



All boards used for SEE testing were fully checked for functionality. Dry runs were also performed to make sure that the test system was stable under all bias and load conditions prior to being taken to the TAMU facility. During the heavy-ion testing, the LabVIEW control program powered up the TPS7H2140-SEP device and set the external sourcing and monitoring functions of the external equipment. After functionality and stability was confirmed, the beam shutter was opened to expose the device to the heavy-ion beam. The shutter remained open until the target fluence was achieved (determined by external detectors and counters). During irradiation, the MSO and NI scope cards continuously monitored the signals. When OUT_X exceeded the predefined 3% window triggers, CS exceeded the predefined 4% window triggers, or when the FAULT signal changed from high to low (using a negative edge trigger), a data capture was initiated. In addition to monitoring the voltage levels from the scopes, VIN current and the 5-V signal from TAMU were monitored at all times. No sudden increases in current were observed (outside of normal fluctuations) on any of the test runs and indicated that SEL or SEB/SEGR events did not occur during any of the tests.



Figure 6-1. Block Diagram of SEE Test Setup with the TPS7H2140-SEP

7 Destructive Single-Event Effects (DSEE) 7.1 Single-Event Latch-up (SEL) Results

During SEL characterization, the device was heated using a TDH35P10R0JE discrete power resistor soldered right under the thermal vias on the bottom layer of the board, maintaining the DUT temperature at 125°C. Prior to radiation, the die to thermocouple temperature was verified using a FLIR IR-camera.

The species used for the SEL testing was a silver (¹⁰⁹Ag) ion with an angle-of-incidence of 0° for an LET_{EFF} = 48 MeV × cm² / mg. For more details, see Section 5). The kinetic energy in the vacuum for this ion is 1.634 GeV (15-MeV /amu line). Flux of approximately 10^5 ions / cm² × s and a fluence of approximately 10^7 ions / cm² were used for the six runs. Run duration to achieve this fluence was approximately two minutes. The six devices were powered up and exposed to the heavy-ions using the maximum recommended voltage of 32 V and maximum load of 5.4 A (1.35 A per channel). The device was set up with OUT₁ operating in a single configuration and OUT₂, OUT₃, OUT₄ were operated in a parallel configuration. See Figure 6-1 for more details. OUT₁ was loaded to 1.35 A, while OUT₂, OUT₃, and OUT₄ were in parallel loaded to 4.05 A (1.35 A per channel). No SEL events were observed during all six runs, which indicates that the TPS7H2140-SEP is SEL-free. Table 7-1 lists the SEL test conditions and results. Figure 7-1 shows a typical plot of I_{IN} versus time for run 1.

Table 7-1. Summary of TPS7H2140-SEP SEL Test Condition and Results

Pre-Production units refers to P-type symbolized units. Productions units refers to units that went through the entire -SEP flow.

Run Number	Type of Unit	Unit Number	lon	LET _{EFF} (MeV × cm ² / mg)	FLUX (ions × cm² / mg)	Fluence (Number ions)
1	Preproduction	2	¹⁰⁹ Ag	48	1.20 × 10 ⁵	9.95 × 10 ⁶
2	Preproduction	3	¹⁰⁹ Ag	48	8.20 × 10 ⁴	9.98 × 10 ⁶
3	Preproduction	4	¹⁰⁹ Ag	48	1.04 × 10 ⁵	1.00 × 10 ⁷
4	Production	5	¹⁰⁹ Ag	48	2.70 × 10 ⁵	9.85 × 10 ⁶
5	Production	6	¹⁰⁹ Ag	48	1.02 × 10 ⁵	1.00 × 10 ⁷
6	Production	7	¹⁰⁹ Ag	48	1.00 × 10 ⁵	1.00 × 10 ⁷

Using the MFTF method shown in *Single-Event Effects (SEE) Confidence Interval Calculations* and combining (or summing) the fluences of the six runs at 125° C (5.78×10^{7}), the upper-bound cross-section (using a 95% confidence level) is calculated as:

$$\sigma_{SEL}\,\leq\,6.38\,\times\,10^{-8}\,cm^2$$
 / device for LET_{EFF}\,=\,48\,MeV\,\times\,cm^2/mg and $T_{I}\,=\,125^{\circ}C$.



Figure 7-1. I_{IN} versus Time for Run 1 of the TPS7H2140-SEP at T_J = 125°C



7.2 Single-Event Burnout (SEB) and Single-Event Gate Rupture (SEGR) Results

The species used for the SEL testing was a silver (¹⁰⁹Ag) ion with an angle-of-incidence of 0° for an LET_{EFF} = 48 MeV × cm² / mg. For more details, see Section 5). The kinetic energy in the vacuum for this ion is 1.634 GeV (15-MeV / amu line). Flux of approximately 10⁵ ions / cm² × s and a fluence of approximately 10⁷ ions / cm² were used for the twelve runs. Run duration to achieve this fluence was approximately two minutes. The six devices were powered up using the recommended maximum voltage of 32 V and the maximum load of 5.4 A (1.35 A per channel). The device was set up with OUT₁ operating in a single configuration. OUT₂, OUT₃, OUT₄ were operated in a parallel configuration. See Figure 6-1 for more details. OUT₁ was loaded to 1.35-A, while OUT₂, OUT₃, and OUT₄ were in parallel loaded to 4.05 A(1.35 A per channel). The TPS7H2140-SEP was tested under enabled and disabled modes. The device was disabled by using an external power supply on the EN_X test points. During SEB/SEGR testing with the device disabled, no OUT_X transient or input current events were observed. No SEB/SEGR free up to LET_{EFF} = 48 MeV × cm² / mg and across the full electrical specifications. Table 7-2 lists the SEB test conditions and results. Figure 7-2 and Figure 7-3 show a plot of the current versus time for run 7 (enabled) and run 8 (disabled).

Table 7-2. Summary of TPS7H2140-SEP SEB Test Condition and Results

Pre-Production units refers to P-type symbolized units. Productions units refers to units that went through the entire -SEP flow.

Run Number	Type of Unit	Unit Number	lon	LET _{EFF} (MeV × cm ² / mg)	Flux (ions × cm²/ mg)	Fluence (Number ions)	Enabled Status
7	Preproduction	2	¹⁰⁹ Ag	48	1.14 × 10 ⁵	9.97 × 10 ⁶	Enabled
8	Preproduction	2	¹⁰⁹ Ag	48	1.18 × 10 ⁵	1.00 × 10 ⁷	Disabled
9	Preproduction	3	¹⁰⁹ Ag	48	1.01 × 10 ⁵	1.00 × 10 ⁷	Enabled
10	Preproduction	3	¹⁰⁹ Ag	48	8.45 × 10 ⁴	1.00 × 10 ⁷	Disabled
11	Preproduction	4	¹⁰⁹ Ag	48	1.03 × 10 ⁵	1.00 × 10 ⁷	Enabled
12	Preproduction	4	¹⁰⁹ Ag	48	1.04 × 10 ⁵	1.00 × 10 ⁷	Disabled
13	Production	5	¹⁰⁹ Ag	48	1.11 × 10 ⁵	1.00 × 10 ⁷	Enabled
14	Production	5	¹⁰⁹ Ag	48	9.96 × 10 ⁴	1.00 × 10 ⁷	Disabled
15	Production	6	¹⁰⁹ Ag	48	1.00 × 10 ⁵	9.96 × 10 ⁶	Enabled
16	Production	6	¹⁰⁹ Ag	48	1.00 × 10 ⁵	1.00 × 10 ⁷	Disabled
17	Production	7	¹⁰⁹ Ag	48	1.00 × 10 ⁵	1.00 × 10 ⁷	Enabled
18	Production	7	¹⁰⁹ Ag	48	1.00 × 10 ⁵	1.00 × 10 ⁷	Disabled

Using the MFTF method shown in *Single-Event Effects (SEE) Confidence Interval Calculations* and combining (or summing) the fluences of the twelve runs at 25°C (11.93×10^7), the upper-bound cross-section (using a 95% confidence level) is calculated as:



 $\sigma_{SEB} \leq 3.09 \times 10^{-8} \, \text{cm}^2$ / device for LET_{EFF} = 48 MeV $\times \, \text{cm}^2$ /mg and T_I = 25°C



8 Single-Event Transients (SET)

SETs are defined as heavy-ion-induced transients upsets on the OUT_X , the CS pin, and the FAULT pin of the TPS7H2140-SEP. SET testing was performed at room temperature (no external temperature control applied). The species used for the SET testing was ¹⁰⁹Ag for a LET_{EFF} = 48 MeV × cm² / mg. For more details, see Section 5. Flux of approximately 10⁵ ions / cm² × s and a fluence of approximately 10⁷ ions / cm² were used for the SET runs.

One unit was tested across multiple input and output conditions to determine the worst case setup for SETs. This unit was tested with a V_{IN} of 4.5, 12, and 28 V with loads of 2 A (0.5 A per channel) and 5.4 A (1.35 A per channel.) The worst case condition was found to be minimum V_{IN} (4.5 V) and a low load, 2 A (0.5 A per channel), was shown to be the worst case in transients for OUT_X, which is considered to be the most important signal. All five other units were only characterized at the worst case SET scenario.

 OUT_X SETs were characterized using a window trigger of ±3% around the nominal output voltage. To capture the SETs, a MSO58B, two NI PXI-5172 scope cards, and one NI PXI-5160 scope card was used to continuously monitor OUT_X , CS, and FAULT. Each scope was operated independently from each other. The output voltage was monitored by using the TP12 and the TP14 test points on the board, while the CS was monitored using the TP10 test point, and FAULT from the TP9 test point.

The NI scopes were programmed to a sample rate of 10 M samples per second (S / s) and recorded 50 k samples, with a 20% pretrigger reference, in case of an event (trigger).

Under heavy-ions, the TPS7H2140-SEP exhibits three transient upsets that were fully recoverable without requiring external intervention.

- 1. A brief transient of the output voltage (referred here as $V_{OUT,SET}$). For the purpose of this report the transients were characterized for deviations $-3\% \le V_{OUT} \le 3\%$ from the nominal output voltage.
- A brief transient on the Current Sense (CS) pin. For the purpose of this report, the transients were characterized for deviations –4% ≤ V_{CS} ≤ 4% from the nominal output voltage. This type of SET is referred to here as V_{CS,SET}.
- 3. A V_{FAULT} upset \leq nominal 1 V on a negative-edge trigger.

Test conditions and results are listed in Table 8-1. Figure 8-2 shows typical time domain plots for all the different types of the observed SETs. Note that V_{OUT} was not monitored on the scope that V_{CS} was triggered from, and as a result, any V_{CS} drops due to a $V_{OUT,SET}$ occurring cannot be classified.

Table 8-1. Summary of TPS7H2140-SEP SET Test Condition and Results

Preproduction units refer to P-type symbolized units. Production units refers to units that completed the entire -SEP flow.

Run Number	Unit Type	Unit Number	lon	LET _{EFF} (MeV × cm²/mg)	FLUX (ions × cm²/ mg)	Fluence (Number ions)	OUT _{1,SET} (Number) ≥ 3%	OUT _{2,SET} (Number) ≥ 3%	CS _{SET} ≥ 4%	FAULT _{SET} ≥ 1-V
19	Preproduction	1	¹⁰⁹ Ag	48	9.98 × 10 ⁴	1.00 × 10 ⁷	849	849	1673	25
20	Preproduction	1	¹⁰⁹ Ag	48	9.80 × 10 ⁴	9.99 × 10 ⁶	314	353	1351	34
21	Preproduction	1	¹⁰⁹ Ag	48	9.96 × 10 ⁴	1.00 × 10 ⁷	702	688	1773	17
22	Preproduction	1	¹⁰⁹ Ag	48	9.55 × 10 ⁴	9.98× 10 ⁶	208	204	2226	15
23	Preproduction	1	¹⁰⁹ Ag	48	9.02 × 10 ⁴	9.96 × 10 ⁶	208	204	1519	22
24	Preproduction	1	¹⁰⁹ Ag	48	1.10 × 10 ⁵	9.97 × 10 ⁶	175	175	2341	25
25	Preproduction	2	¹⁰⁹ Ag	48	1.16 × 10 ⁵	9.96 × 10 ⁶	751	759	1381	21
26	Preproduction	3	¹⁰⁹ Ag	48	1.07 × 10 ⁵	1.00 × 10 ⁷	548	849	1417	13
27	Preproduction	4	¹⁰⁹ Ag	48	1.09 × 10 ⁵	1.00 × 10 ⁷	788	775	1530	20
28	Production	5	¹⁰⁹ Ag	48	1.19 × 10 ⁵	1.00 × 10 ⁷	830	830	4879	25
29	Production	6	¹⁰⁹ Ag	48	9.48 × 10 ⁴	9.97 × 10 ⁶	852	852	4910	28

Using the MFTF method shown in *Single-Event Effects (SEE) Confidence Interval Calculations*, the upper-bound cross-section (using a 95% confidence level) is calculated for the different SETs as shown in Table 8-2.

Table 8-2. Upper Bound Cross Section for SETs at 95% Conf	fidence Interval and Room Temperature
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SET Type	Total Fluence (Number of Ions)	Total Number of Upsets	Upper Bound Cross Section (cm ² / device)
OUT _{1,SET} ≥ 3%		6225	5.89 × 10 ⁻⁵
OUT _{2,SET} ≥ 3%	- 10.83 × 10 ⁷ -	6538	6.19 × 10 ⁻⁵
CS _{SET} ≥ 4%		25000	2.34 × 10 ⁻⁴
FAULT _{SET} ≤ Nominal -1 V		245	2.56 × 10 ⁻⁶



9 Event Rate Calculations

Event rates were calculated for LEO (ISS) and GEO environments by combining CREME96 orbital integral flux estimations and simplified SEE cross-sections according to methods shown in *Heavy Ion Orbital Environment Single-Event Effects Estimations*. A minimum shielding configuration of 100 mils (2.54 mm) of aluminum, and "worst-week" solar activity is assumed. (This is similar to a 99% upper bound for the environment.) Using the 95% upper-bounds for the SEL and the SEB/SEGR, the event rate calculation for the SEL and the SEB/SEGR is listed in Table 9-1 and Table 9-2, respectively. Note that this number is for reference since no SEL or SEB/SEGR events were observed.

Table 9-1. SEL	. Event Rate	Calculations	for Worst-Week	LEO and	GEO Orbits
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Orbit Type	Onset LET _{EFF} (MeV-cm ² / mg)	CREME96 Integral FLUX (per day / cm ²)	σSAT (cm²)	Event Rate (per day)	Event Rate (FIT)	MTBE (Years)
LEO (ISS)	- 48	4.50 × 10 ⁻⁴	6 38 × 10 ⁻⁸	2.87 × 10 ⁻¹¹	1.20 × 10 ⁻³	9.54 × 10 ⁷
GEO		1.48 × 10 ⁻³	0.30 ~ 10	9.42 × 10 ⁻¹¹	3.93 × 10 ⁻³	2.91 × 10 ⁷

Table 9-2. SEB/SEGR Event Rate Calculations for Worst-Week LEO and GEO Orbits

Orbit Type	Onset LET _{EFF} (MeV-cm ² / mg)	CREME96 Integral FLUX (per day / cm ²)	σSAT (cm²)	Event Rate (per day)	Event Rate (FIT)	MTBE (Years)
LEO (ISS)	18	4.50 × 10 ⁻⁴	3 00 × 10 ⁻⁸	1.39 × 10 ⁻¹¹	5.80 × 10 ⁻⁴	1.97 × 10 ⁸
GEO	40	1.48 × 10 ⁻³	5.03 ~ 10	4.56 × 10 ⁻¹¹	1.90 × 10 ⁻³	6.00 × 10 ⁷



10 Summary

The purpose of this study was to characterize the effect of heavy-ion irradiation on the single-event effect (SEE) performance of the TPS7H2140-SEP quad-channel eFuse. Heavy-ions with LET_{EFF} = 48 MeV × cm²/mg were used for the SEE characterization campaign. Flux of 10⁵ ions / cm² × s and fluences to 1 × 10⁷ ions / cm² per run were used for the characterization. The SEE results demonstrated that the TPS7H2140-SEP eFuse is free of destructive SEB events and SEL-free up to LET_{EFF} = 48 MeV × cm² / mg and across the full electrical specifications. Transients at LET_{EFF} = 48 MeV × cm² / mg are discussed. CREME96-based worst-week event-rate calculations for LEO (ISS) and GEO orbits for the DSEE are shown for reference.



11 References

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